

<b>Notice of References Cited</b>			Application No. 09/093,291	Applicant(s) Van Buskirk et al.		
			Examiner Allan Olsen	Group Art Unit 1746	Page 1 of 1	
<b>U.S. PATENT DOCUMENTS</b>						
*	DOCUMENT NO.	DATE	NAME		CLASS	SUBCLASS
x A	6,018,065	1/2000	Baum et al.		556	136
B						
C						
D						
E						
F						
G						
H						
I						
J						
K						
L						
M						
<b>FOREIGN PATENT DOCUMENTS</b>						
*	DOCUMENT NO.	DATE	COUNTRY	NAME	CLASS	SUBCLASS
N						
O						
P						
Q						
R						
S						
T						
<b>NON-PATENT DOCUMENTS</b>						
*	DOCUMENT (Including Author, Title, Source, and Pertinent Pages)				DATE	
x u	Floy I. Chang et al., Gas-Phase Silicon Micromachining with Xenon Difluoride, Proc. of SPIE vol.2641, pp 117-128				12/1995	
v						
w						
x						

\* A copy of this reference is not being furnished with this Office action.  
(See Manual of Patent Examining Procedure, Section 707.05(e).)